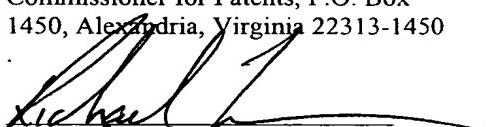


PATENT
30205/39511

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Seong Hwan Park et al.)
Serial No.: To be assigned)
Filed: November 26, 2003 (Herewith))
For: Method of Manufacturing)
Semiconductor Device)
Group Art Unit: To be assigned)
Examiner: To be assigned)
)
)
)
)

I hereby certify that this paper and the documents referred to as enclosed therewith are being deposited with the United States Postal Service as Express Mail, Airbill No. EV323777167US postage prepaid, on November 26, 2003, in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450


Richard Zimmermann

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Submitted herewith for consideration by the examiner is a copy of the document identified on the attached Form PTO-1449. Entry and consideration of the submitted document is solicited.

The Commissioner is authorized to charge any fee deficiency required by this paper, or credit any overpayment, to Deposit Account No. 13-2855.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP
6300 Sears Tower
233 South Wacker Drive
Chicago, Illinois 60606-6357
(312) 474-6300

November 26, 2003

By:


Michael R. Hull
Reg. No. 35,902

Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. 30205/39511	Serial No. To be Assigned
INFORMATION DISCLOSURE STATEMENT		Applicant Seong Hwan Park	
		Filing Date November 26, 2003	Group To be Assigned

U.S. PATENT DOCUMENTS							
*Examiner Initials		Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate

FOREIGN PATENT DOCUMENTS							
*Examiner Initials		Document Number	Publication Date	Country	Class	Subclass	Translation
							Yes No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
		Fujimura et al., "Ashing of the Ion Implanted Resist Layer," Digest of Papers 1989 2 nd MicroProcess Conference, July 2-5, 1989.					

EXAMINER	DATE CONSIDERED
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance <u>and</u> not considered. Include copy of this form with next communication to applicant.</p>	